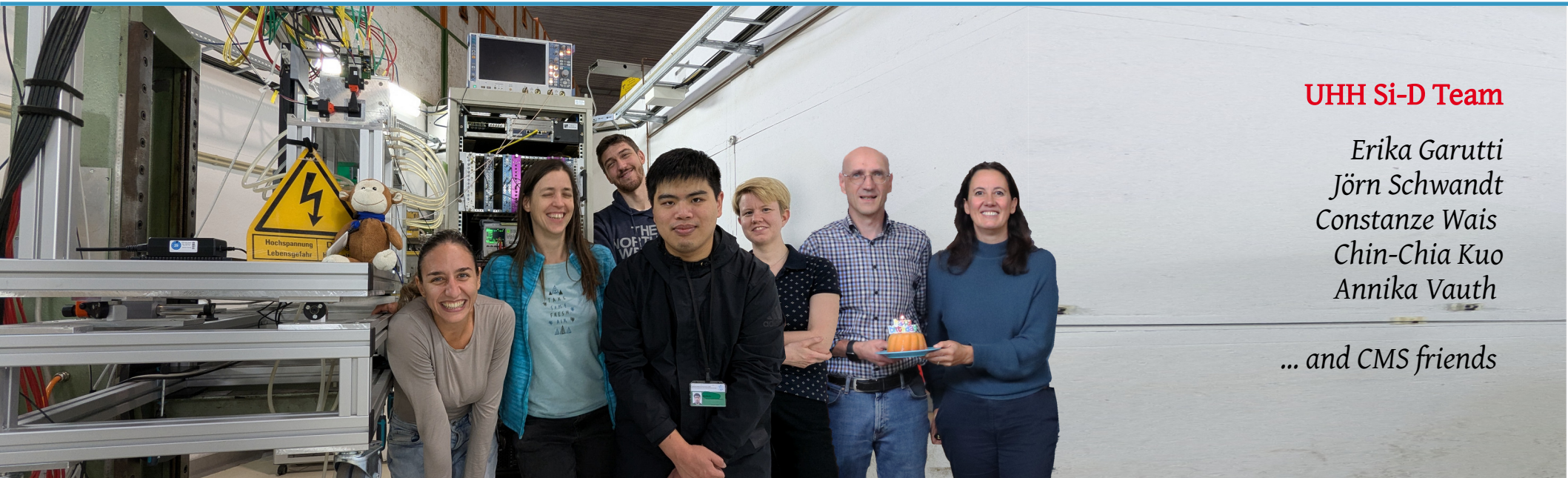


# UHH projects



## UHH Si-D Team

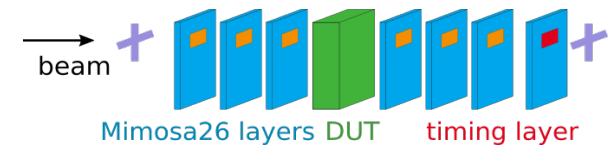
Erika Garutti  
Jörn Schwandt  
Constanze Wais  
Chin-Chia Kuo  
Annika Vauth

... and CMS friends

Si-D consortium meeting

28.01.2025

# LGAD timing layer



WP2.1

- HEP detector R&D: dedicated beam tests for design, calibrations, commissioning, ...
- Testbeam infrastructure includes pixel detectors (“beam telescope”) for reference tracks...
- Current beam telescopes: great spatial resolution ( $\sigma \sim 3 \mu\text{m}$ ), but no timing
- To meet requirements of future detector test campaigns: [add timing layer](#)

Technology choice: Low Gain Avalanche Diodes

Short term: read out with Timepix3

Long term: Timepix4?

First prototypes: Trench-Isolated LGADs (FBK)

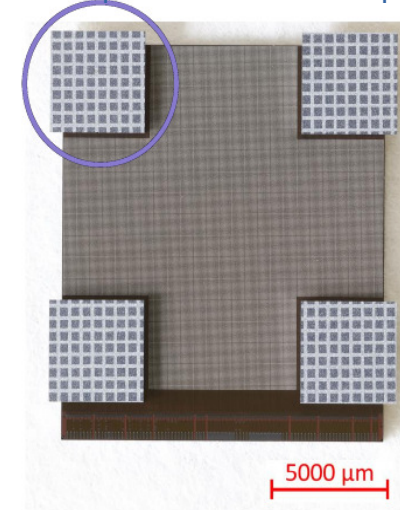
a) small 2x2 pixel samples for characterisation in the lab

→ measurements with IR laser

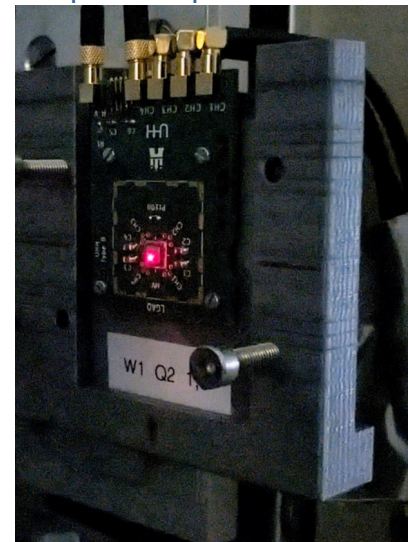
b) 55 $\mu\text{m}$  pitch pixel samples to bond to Timepix3(4)

→ first test in the DESY II testbeam end of last year

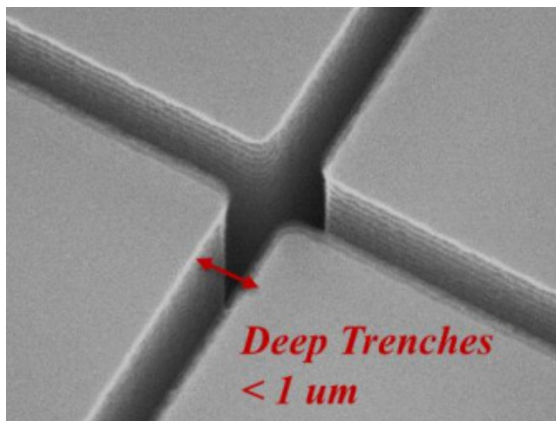
55x55 pixel sensors on Timepix3



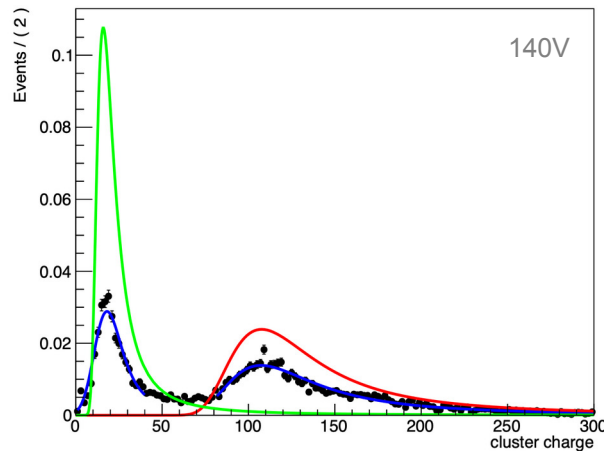
2x2 pixel samples in the lab



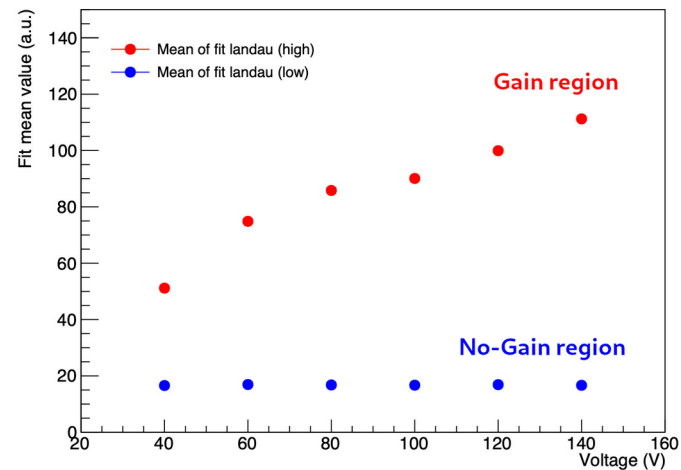
# LGAD testbeam results



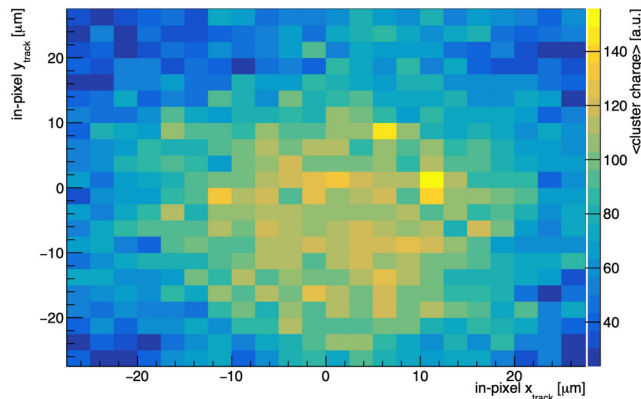
Fitting of charge distribution



Mean of fit landau vs voltage



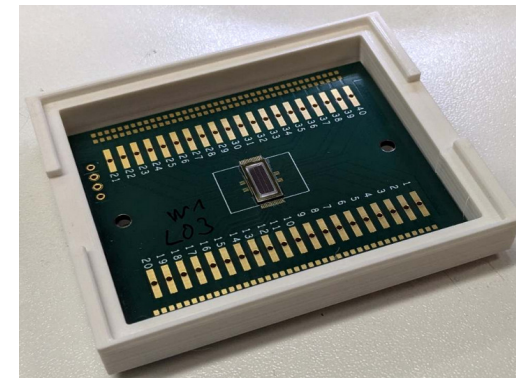
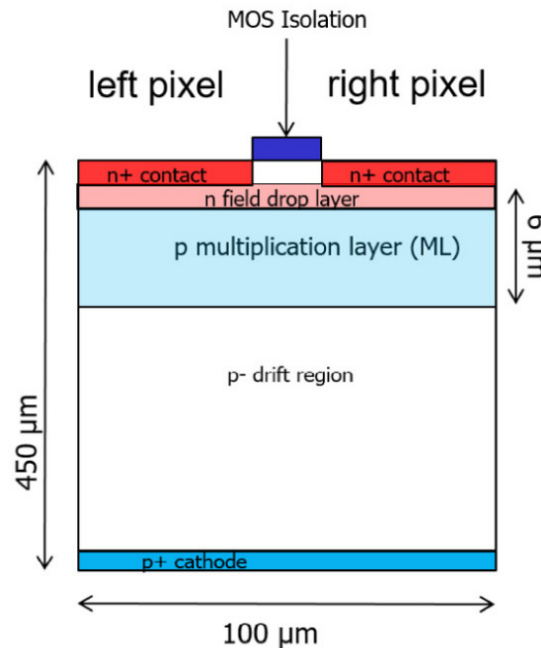
Mean cluster charge map (1-pixel)



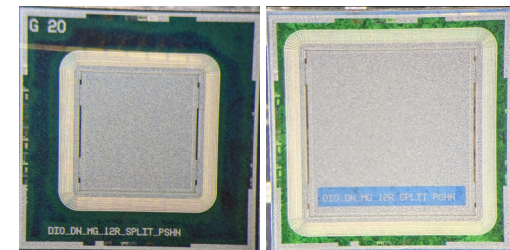
- Assume the landau on the right comes from gain region, while the landau on the left comes from no-gain region
  - Fit with  $Gauss_L * Landau_L + (Gauss_R * Landau_R) \times factor$
  - A short range between two peaks is excluded from fit to mitigate the effect from transition region
- ⇒ Can determine absolute gain



- Conventional LGADs have problems with edge breakdown. Common ways to prevent this, lead to “blindness” in the interpixel region.
- **Monolithic Array of Reach THrough Avalanche photo diodes (MARTHA):** approach developed by HLL-MPG to produce pixelated LGADs
- In addition to preventing the edge breakdown with an additional n-doped layer (FDL), this approach also promises 100% fill factor



Strip sensor on PCB



Diodes

First test structures of two different wafers have already been delivered. These include diodes and strip sensors.

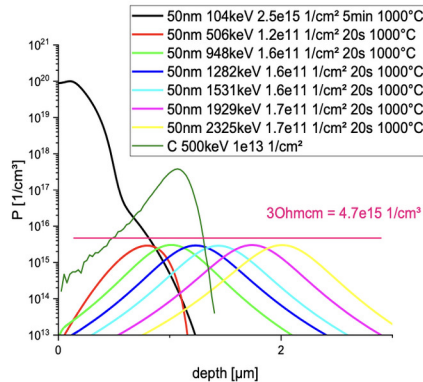
⇒ The analysis of the diodes with C-V and I-V techniques has already started, a readout for the strip sensors has been designed and ordered

# Radiation hardness

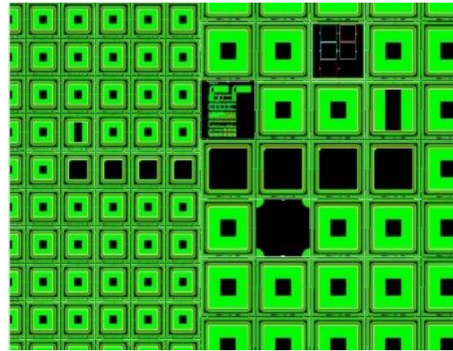
WP3.6

- RD50 project “Defect engineered diodes mimicking the gain layer in LGADs”
- 18 differently defect engineered wafers with respect to B, O and C impurities as well as with P in compensated n<sup>++</sup>-p<sup>+</sup> diodes

P and C implantations in compensated n<sup>++</sup>-p<sup>+</sup> diodes with 50 nm of oxide



layout design including samples for Hall measurements and diodes with fully transparent electrodes.



## Expected results

- Reveal the microscopic radiation induced effects above  $10^{15}$  n<sub>eq</sub>/cm<sup>2</sup> and identify the reasons for losing the gain in LGADs.
- Reveal the role of O, C and P impurities in low resistivity B doped Si and of defects impacting on the gain layers in LGADs
- Detection and characterization of new defects induced by irradiation above  $10^{15}$  n<sub>eq</sub>/cm<sup>2</sup> (e.g. 2<sup>nd</sup> order defects)
- provide real inputs for modelling the radiation damage above  $10^{16}$  n<sub>eq</sub>/cm<sup>2</sup>, allowing the development of accurate parametrization models validated on the entire range of fluences, from low to extreme;

- First samples expected in Feb. 2025 (project will continue within DRD3)